



00862.022172

copy
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent of:)
Yasuhiro SHIMADA et al.) Examiner: K. T. Nguyen
Application No.: 09/819,669) Group Art Unit: 2881
Filed: March 29, 2001)
For: ELECTRON OPTICAL SYSTEM ARRAY, METHOD) July 15, 2005
OF FABRICATING THE SAME, CHARGED-)
PARTICLE BEAM EXPOSURE APPARATUS, AND)
DEVICE MANUFACTURING METHOD)
U.S. Patent No. 6,872,950 B2)
Issued: March 29, 2005)

Certificate
JUL 21 2005
of Correction

The Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450
Attention: Certificate of Correction Branch

REQUEST FOR
CERTIFICATE OF CORRECTION
UNDER RULE 322

Sir:

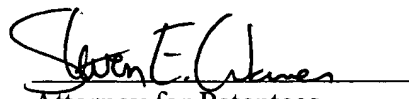
Patentees request that a Certificate of Correction be issued by the Patent and
Trademark Office due to errors which appear in the printed patent as a result of Patent and
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No fee is believed to be due with the filing of this paper. Nevertheless, the Commissioner may charge Deposit Account No. 06-1205 should any fee be deemed necessary for filing this paper.

Patentees' undersigned attorney may be reached in our Washington, D.C. Office by telephone at (202) 530-1010. All correspondence should continue to be directed to our below-listed address.

Respectfully submitted,


Attorney for Patentees
Steven E. Warner
Registration No. 33,326

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30 Rockefeller Plaza
New York, New York 10112-3801
Facsimile: (212) 218-2200
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UNITED STATES PATENT AND TRADEMARK OFFICE
CERTIFICATE OF CORRECTION

PATENT NO. : 6,872,950 B2

DATED : March 29, 2005

INVENTOR(S): Yasuhiro SHIMADA et al.

Page 1 of 1

It is certified that error appears in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

ON THE COVER PAGE:

In item “(56) **References Cited**,” under “OTHER PUBLICATIONS,” the third-listed article “‘Arrayed Miniature Electron Beam Columns for High Throughput Sub-100 nm Lithography,’ T. H. P. CHang, et al., Journal of Vacuum Science and Technology B, vol. 10, No. 6, Nov./Dec. 1992, pp. 2743-2748.” should read -- “Arrayed Miniature Electron Beam Columns for High Throughput Sub-100 nm Lithography, T. H. P. Chang, et al., Journal of Vacuum Science and Technology B, vol. 10, No. 6, Nov./Dec. 1992, pp 2743-2748. --

On page 2 of the Cover Page, item “(56) **References Cited**,” “U.S. PATENT DOCUMENTS,” continued, the second-listed document of the second column, “6,381,072 B1 4/2002 Burger.....359/622” should be deleted.

COLUMN 19:

Line 10, “sunport” should read -- support --.

MAILING ADDRESS OF SENDER:

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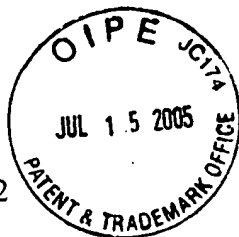
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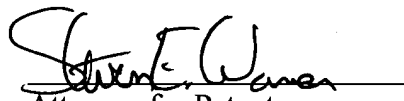
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